

# Improved electrical characteristic of MoS<sub>2</sub> on two-dimensional TMPS<sub>3</sub>

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Molybdenum disulfide (MoS<sub>2</sub>) has been studied for complementary of graphene because of its intrinsic bandgap and high mobility. While atomic thickness and dangling-bond-free surface can make us to consider MoS<sub>2</sub> as a promising candidate for short channel devices, these properties make the deposition of high-k dielectrics on MoS<sub>2</sub> challenges, which results in the threshold voltage instability induced by high-density traps and make hard to deposit on transistors [1,2].

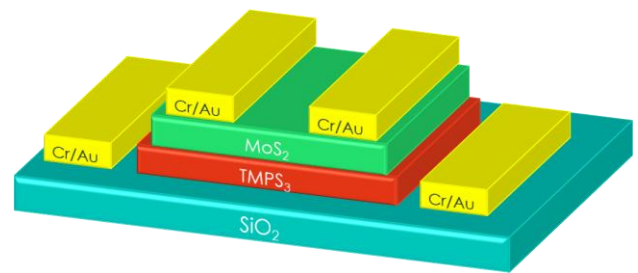
Given that graphene on high-k SrTiO<sub>3</sub> epitaxial thin film get influence and protect from the charges nearby layer [3], we deposited MoS<sub>2</sub> on TMPS<sub>3</sub>, which is another 2D material and shows various high-k dielectrics dependent on constructed transition metal. Also, controlling thickness of TMPS<sub>3</sub> through mechanical exfoliation can facilitate the improvement of electrical characteristics of MoS<sub>2</sub>. These results can be explained by not only mitigating adverse effect from SiO<sub>2</sub> substrate but also enhancement of electrical properties of MoS<sub>2</sub> when integrated with high-k materials.

We fabricate metal/TMPS<sub>3</sub>/MoS<sub>2</sub> structure using mechanical exfoliation and dry transfer method. As gate voltage is applied from -100V to 100V progressively, improved current flow is shown in results. Also, enhanced mobility about 48cm<sup>2</sup>/Vs is represented in our study.

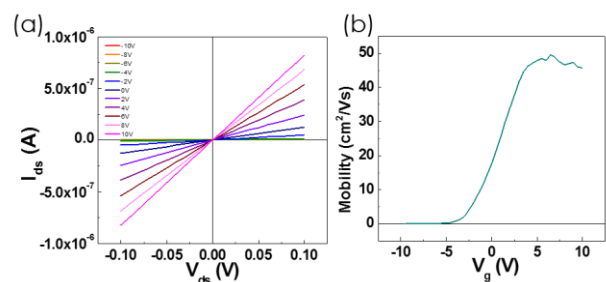
## References

- [1] Jingli Wang *et al.*, *Advanced Materials*, 37 (2016) 8302-8308
- [2] Qingkai Qian *et al.*, *Scientific Reports*, 6:27676 (2016) 1-9
- [3] Jeongmin Park *et al.*, *Nano Letters*, 16 (2016) 1754-1759

## Figures



**Figure 1:** The schematic of TMPS<sub>3</sub>/MoS<sub>2</sub> on SiO<sub>2</sub> substrate



**Figure 2:** (a)  $I_{ds}$ - $V_{ds}$  curve of MoS<sub>2</sub> as applied gate voltage from -100V to 100V and (b) mobility of MoS<sub>2</sub> on FePS<sub>3</sub>